

cont'd
b1

wherein the dummy diffused layer has its surface covered with an anti-silicidation film at least partially, on which no gate electrode is provided.

14. (Amended) A semiconductor device comprising:

a substrate;

a source/drain diffused layer formed in the substrate for a transistor; and

a dummy diffused layer formed in the substrate,

wherein the source/drain diffused layer has its surface silicided, and

wherein the dummy diffused layer has its surface covered with an anti-silicidation film at least partially, and

wherein the dummy diffused layer is located between an analog circuit block and

b2

a digital circuit block.

15. (Amended) A semiconductor device comprising:

a substrate;

a source/drain diffused layer formed in the substrate for a transistor; and

a dummy diffused layer formed in the substrate,

wherein the source/drain diffused layer has its surface silicided, and

wherein the dummy diffused layer has its surface covered with an anti-silicidation film at least partially, and

wherein the dummy diffused layer is not electrically coupled to another component via an interconnect.